

Electronic Patent Application Fee Transmittal

Application Number:	10812411			
Filing Date:	30-Mar-2004			
Title of Invention:	EUV lithography system and chuck for releasing reticle in a vacuum isolated environment			
First Named Inventor/Applicant Name:	Siegfried Schwarzl			
Filer:	Ira Stuart Matsil/Natalie Swider			
Attorney Docket Number:	QIM 2004 P 50143 US			
Filed as Large Entity				
Utility Filing Fees				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
Post-Allowance-and-Post-Issuance:				
Extension-of-Time:				
Extension - 2 months with \$0 paid	1252	1	460	460

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Total in USD (\$)				460